

Rewrite claim 4 as follows:

Sub D2
B2 4. (Twice Amended) A method of storing a silicon wafer in water, comprising the steps of preparing storage water containing Cu at a concentration of 0.01 ppb or less and a surfactant, and storing a silicon wafer in the prepared storage water.

Cancel claim 5, without prejudice.

Rewrite claim 7 as follows:

B3 7. (Twice Amended) A method of storing a silicon wafer in water according to claim 4, wherein the step of storing a silicon wafer includes providing a silicon wafer having a hydrophobic surface.

Rewrite claim 9 as follows:

B4 9. (Twice Amended) A method of storing a silicon wafer in water according to claim 4, wherein the step of storing the silicon wafer comprises storing the silicon wafer immediately after polishing.

Please add the following new claim:

B5 added --21. (New) A regulating method of a storage water, wherein the concentration of Cu in the storage water is regulated to 0.01 ppb or less.--